

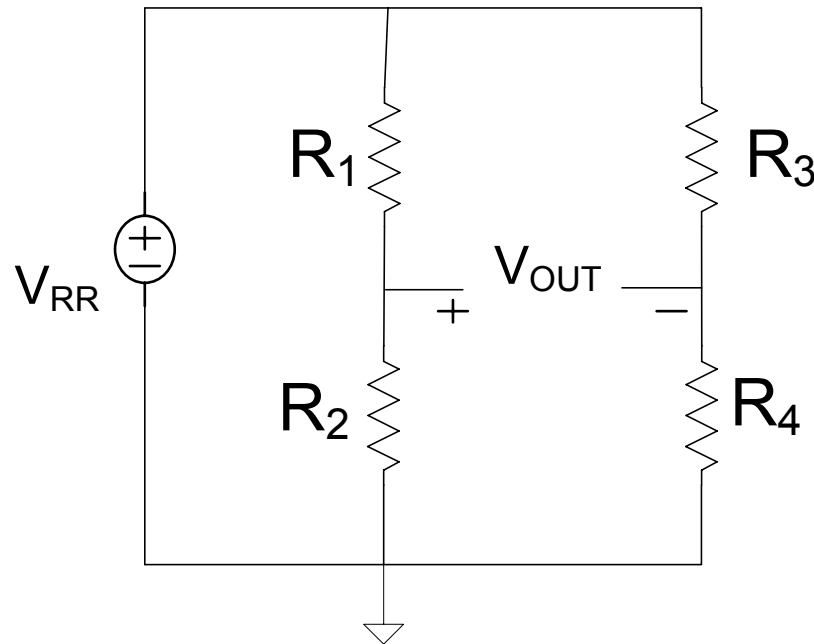
# EE 434

## Lecture 15

Devices in Semiconductor Processes

## Quiz 10

The resistors in this strain-gauge bridge circuit have a temperature coefficient that is  $+200\text{ppm}/^\circ\text{C}$  and measured unstrained resistance value at  $T=300^\circ\text{K}$  of  $100\Omega$ . Assume that the temperature of  $R_4$  was  $30^\circ\text{C}$  higher than that of the remaining resistors which are all operating at  $300^\circ\text{K}$ . If the signal information is carried in the change in  $R_2$  which is  $0.01\Omega$ . What percent error in  $V_{\text{OUT}}$  is introduced by the temperature variation of  $R_4$ ?



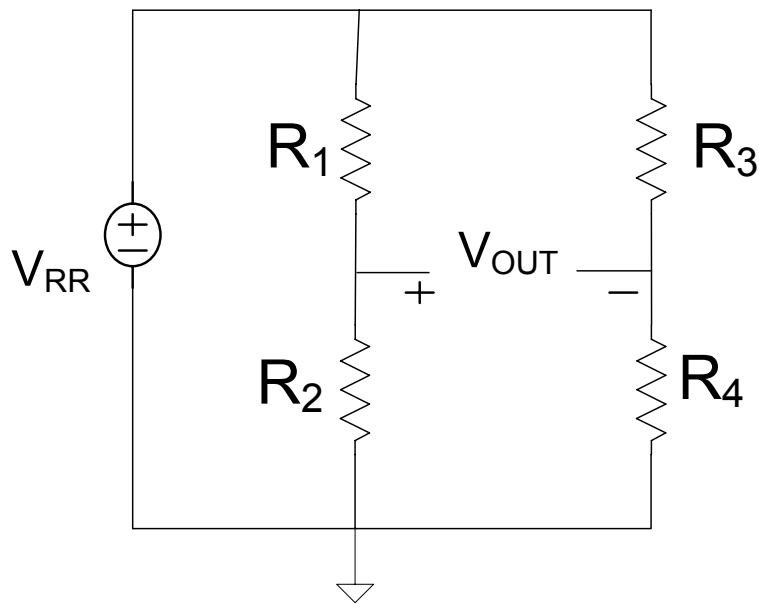
And the number is ....

1            8            7            5            3  
6            9            4            2

**3**

## Quiz 10      Solution:

The resistors in this strain-gauge bridge circuit have a temperature coefficient that is +200ppm/°C and measured unstrained resistance value at T=300°K of 100Ω. Assume that the temperature of R<sub>4</sub> was 30°C higher than that of the remaining resistors which are all operating at 300°K. If the signal information is carried in the change in R<sub>2</sub> which is 0.01Ω. What percent error in V<sub>OUT</sub> is introduced by the temperature variation of R<sub>4</sub>?



$$V_{\text{OUTD}} = V_{\text{RR}} \left( \frac{R_{2A}}{R_{1N} + R_{2A}} - \frac{R_{4N}}{R_{4N} + R_{3N}} \right)$$

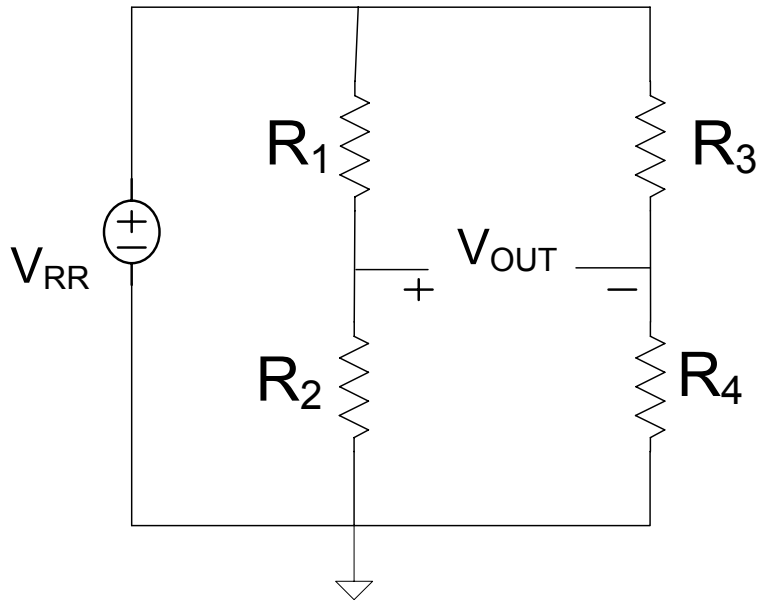
$$V_{\text{OUTD}} = V_{\text{RR}} \left( \frac{100.01}{200.01} - \frac{100}{200} \right) = V_{\text{RR}} (2.49\text{E} - 5)$$

$$R_4(T_2) \approx R_4(T_1) \left[ 1 + (T_2 - T_1) \frac{\text{TCR}}{10^6} \right]$$

$$R_4(T_2) \approx 100 \left[ 1 + (30) \frac{200}{10^6} \right] = 100.6\Omega$$

# Quiz 10

Solution:



$$V_{OUTD} = V_{RR} \left( \frac{100.01}{200.01} - \frac{100}{200} \right) = V_{RR} (2.49E - 5)$$

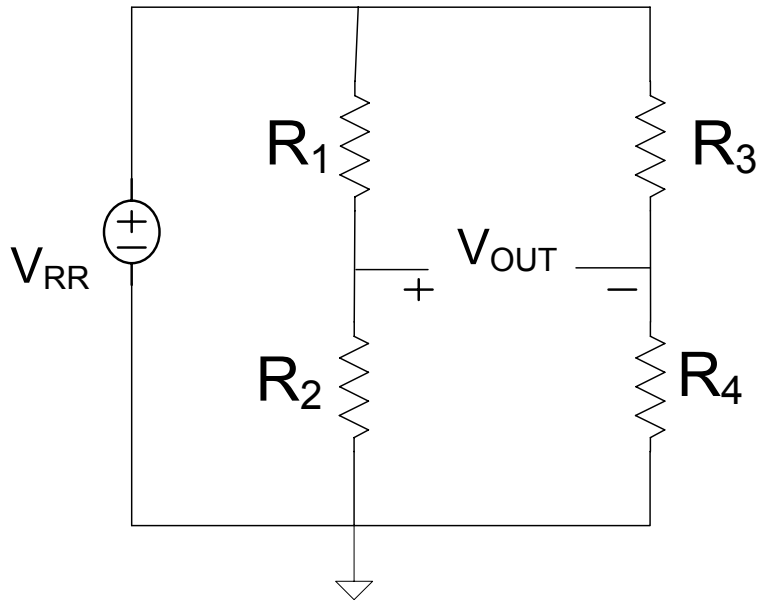
$$V_{OUTA} = V_{RR} \left( \frac{R_{2A}}{R_{1N} + R_{2A}} - \frac{R_{4NT}}{R_{4NT} + R_{3N}} \right)$$

$$V_{OUTA} = V_{RR} \left( \frac{100.01}{100 + 100.01} - \frac{100.6}{100.6 + 100} \right) = V_{RR} (1.47E - 3)$$

$$\text{Error} = \frac{V_{OUTD} - V_{OUTA}}{V_{OUTD}} 100\% = \frac{2.49E - 5 - 1.47E - 3}{2.49E - 5} 100\%$$

# Quiz 10

Solution:



$$V_{OUTD} = V_{RR} \left( \frac{100.01}{200.01} - \frac{100}{200} \right) = V_{RR} (2.49E-5)$$

$$V_{OUTA} = V_{RR} \left( \frac{R_{2A}}{R_{1N} + R_{2A}} - \frac{R_{4NT}}{R_{4NT} + R_{3N}} \right)$$

$$V_{OUTA} = V_{RR} \left( \frac{100.01}{100 + 100.01} - \frac{100.6}{100.6 + 100} \right) = V_{RR} (1.47E-3)$$

$$\text{Error} = \frac{V_{OUTD} - V_{OUTA}}{V_{OUTD}} 100\% = \frac{2.49E-5 - 1.47E-3}{2.49E-5} 100\%$$

$$\text{Error} = 5800\%$$

Review from Last Time

# Basic Devices and Device Models

- Resistor

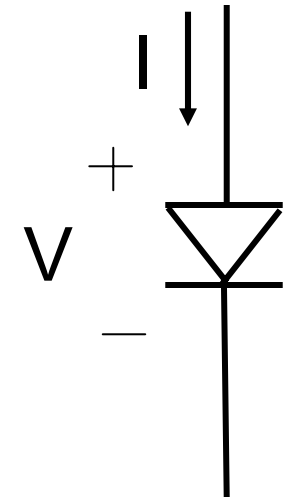
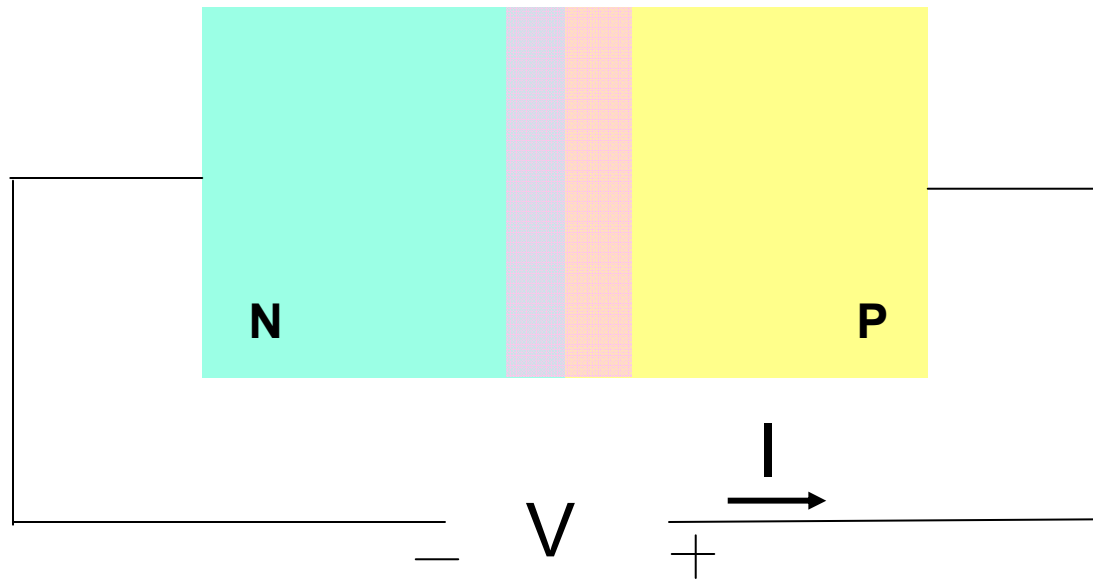
 Diode

 Capacitor

- MOSFET
- BJT

## Review from Last Time

# pn Junctions



Diode Equation:

$$I = \begin{cases} J_S A e^{\frac{v}{nV_T}} & V > 0 \\ 0 & V < 0 \end{cases}$$

$J_S$  = Sat Current Density  
 $A$  = Junction Cross Section Area  
 $V_T = kT/q$   
 $n$  is approximately 1



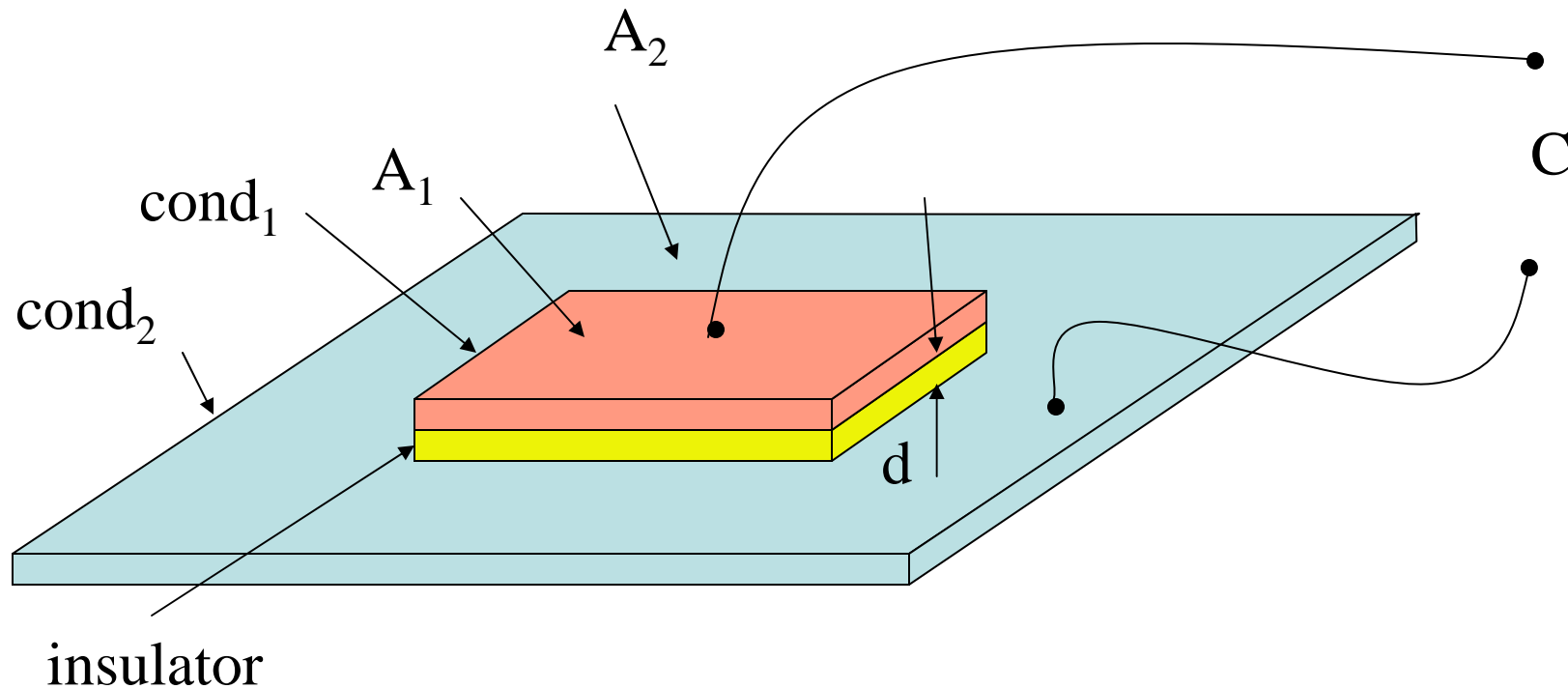
Review from Last Time

# Capacitors

- Types
  - Parallel Plate
  - Fringe
  - Junction

Review from Last Time

# Parallel Plate Capacitors



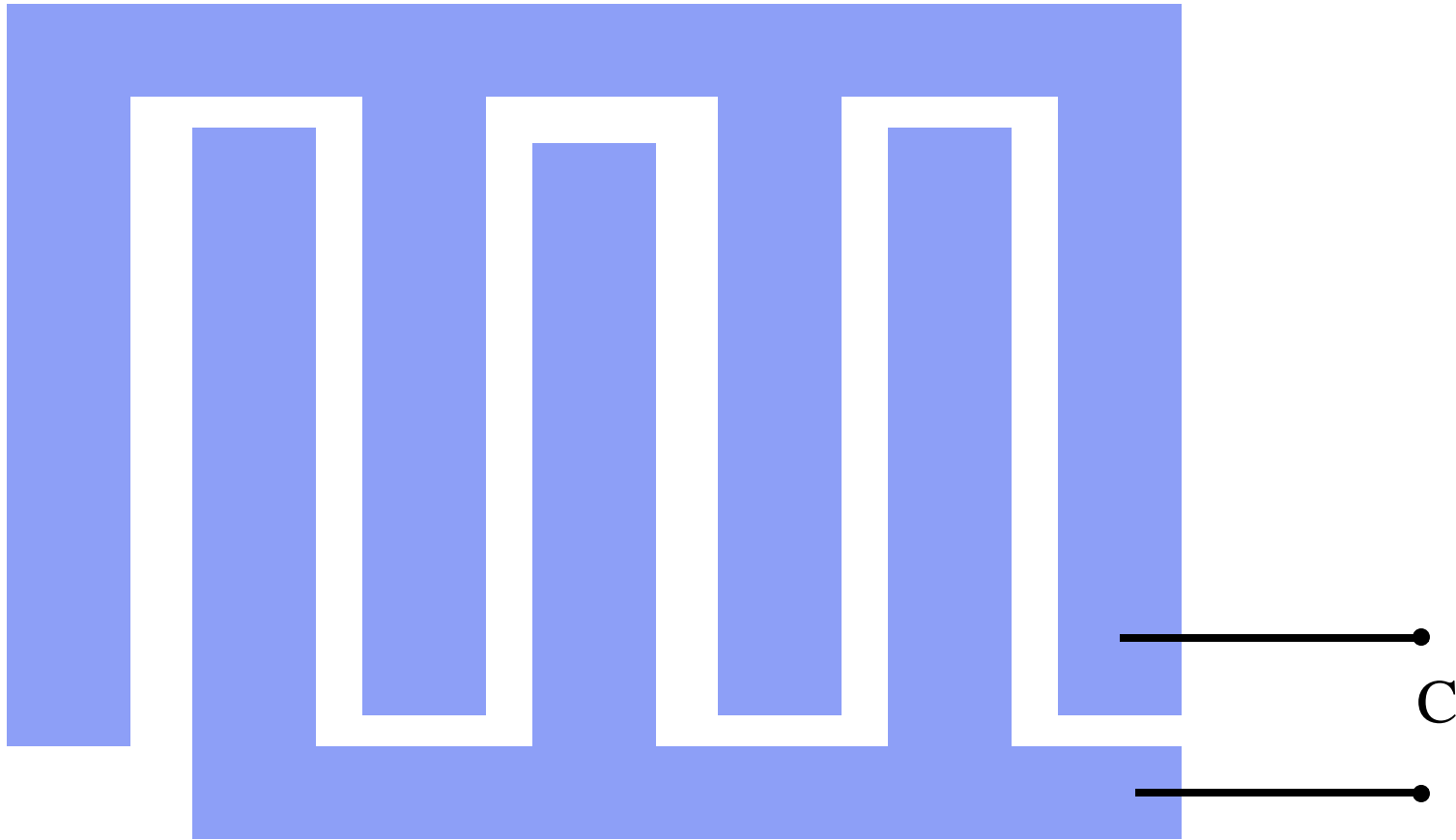
$A$  = area of intersection of  $A_1$  &  $A_2$

One (top) plate **intentionally** sized smaller to determine  $C$

$$C = C_d A$$

Review from Last Time

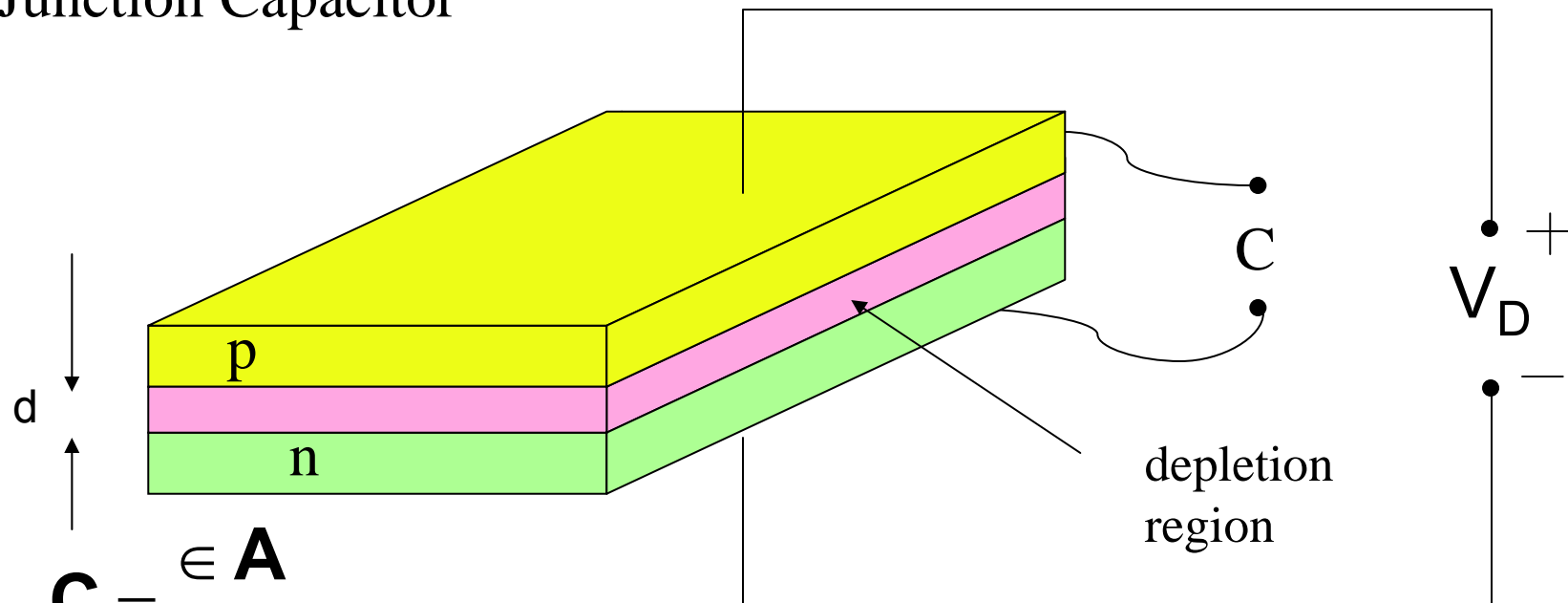
# Fringe Capacitors



## Review from Last Time

# Capacitance

## Junction Capacitor



$$C = \frac{\epsilon A}{d}$$

$$C = \frac{C_{j0} A}{\left(1 - \frac{V_D}{\phi_B}\right)^n}$$

$$\phi_B \approx 0.6V$$


$$\text{for } V_{FB} < \frac{\phi_B}{2}$$

$C_{j0}$ : junction capacitance at  $V_D = 0V$

$\phi_B$ : barrier or built-in potential

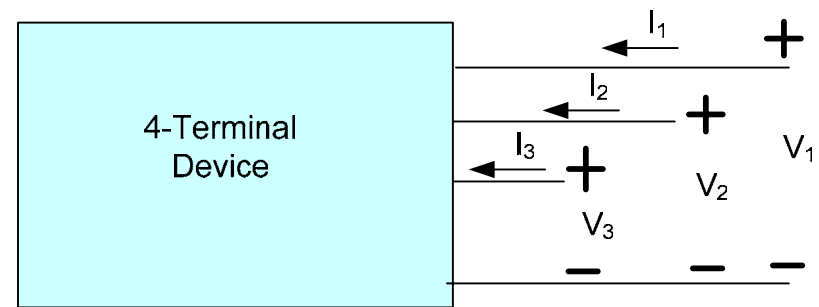
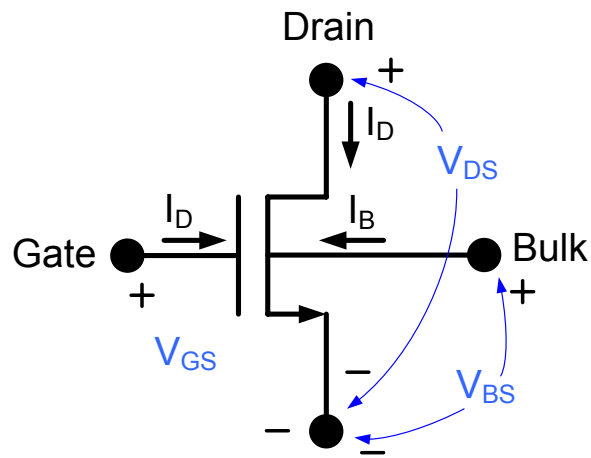
Note:  $d$  is voltage dependent  
-capacitance is voltage dependent  
-usually parasitic caps  
-varicaps or varactor diodes exploit voltage dep. of  $C$

# Basic Devices and Device Models

- Resistor
- Diode
- Capacitor
-  MOSFET
- BJT

# Operation and Modeling of MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.



$$\left. \begin{aligned} I_D &= f_1(V_{GS}, V_{DS}, V_{BS}) \\ I_G &= f_2(V_{GS}, V_{DS}, V_{BS}) \\ I_B &= f_3(V_{GS}, V_{DS}, V_{BS}) \end{aligned} \right\}$$



$$\left. \begin{aligned} I_1 &= f_1(V_1, V_2, V_3) \\ I_2 &= f_2(V_1, V_2, V_3) \\ I_3 &= f_3(V_1, V_2, V_3) \end{aligned} \right\}$$

# Modeling of the MOSFET

## Strategy

Develop multiple models that are useful for specific classes of applications

Use as simple of a model as we can justify

Often must consider a modestly more complicated model to justify a simpler model

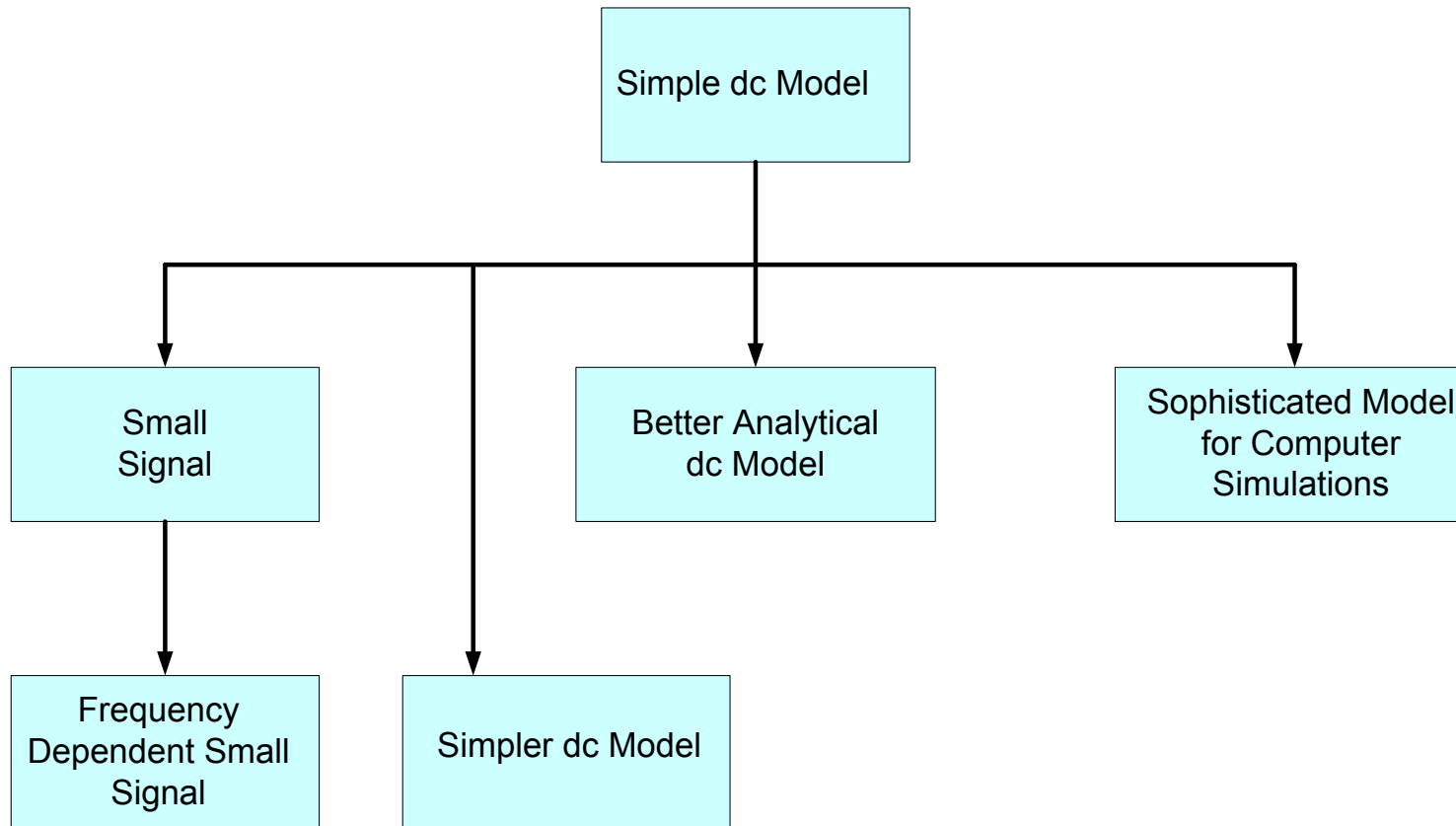
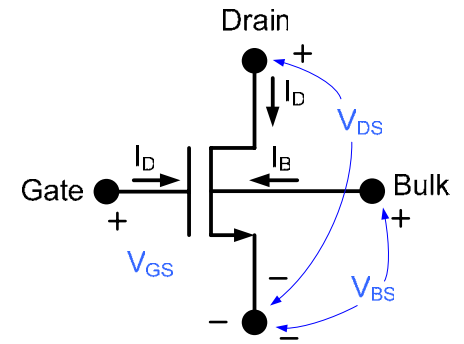
# Modeling of the MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.

$$I_D = f_1(V_{GS}, V_{DS}, V_{BS})$$

$$I_G = f_2(V_{GS}, V_{DS}, V_{BS})$$

$$I_B = f_3(V_{GS}, V_{DS}, V_{BS})$$

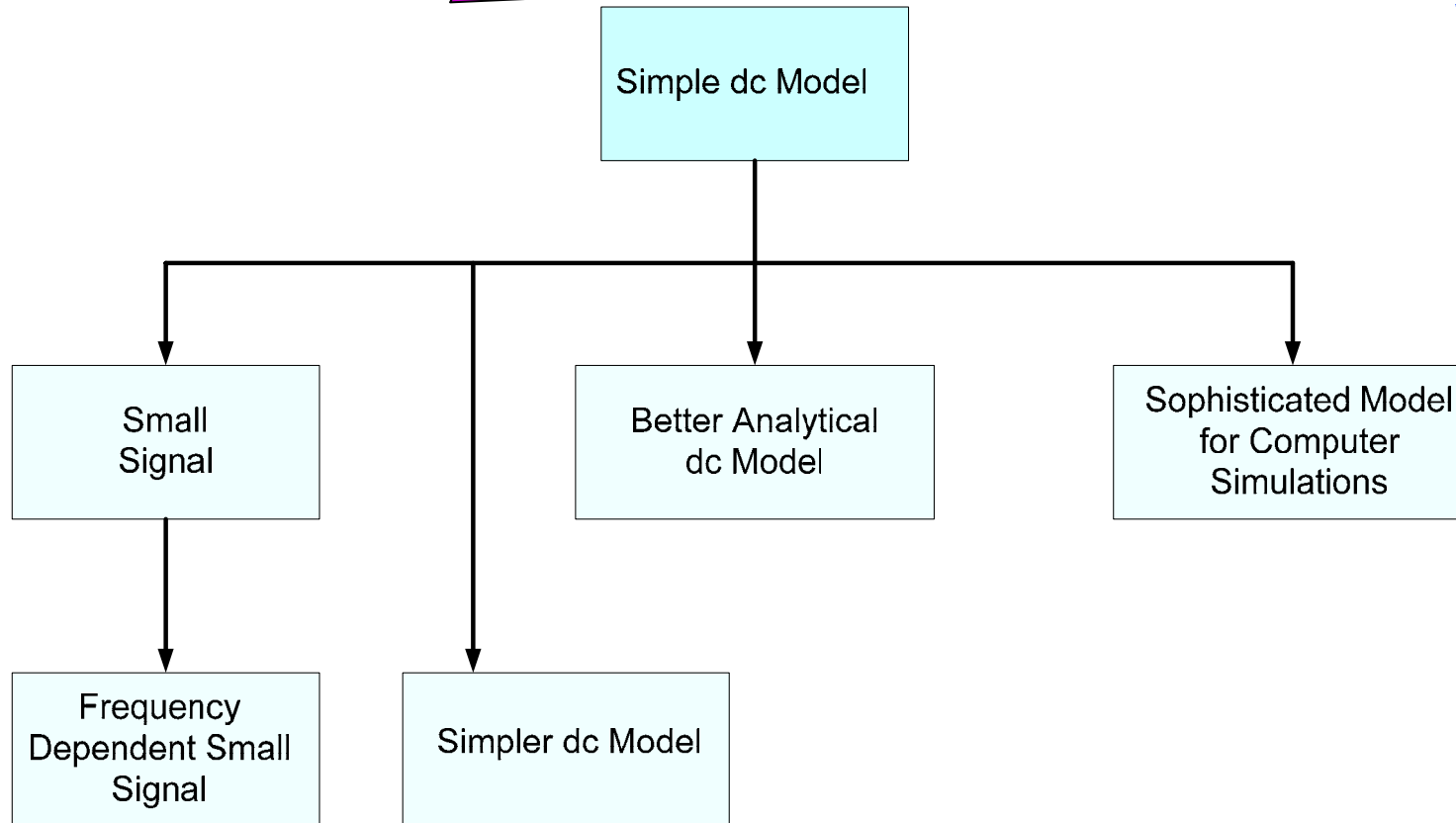
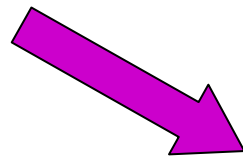
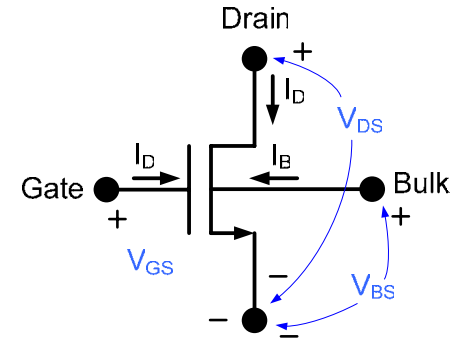




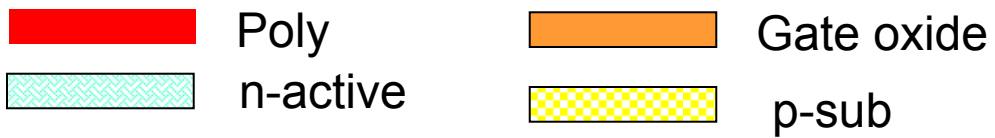
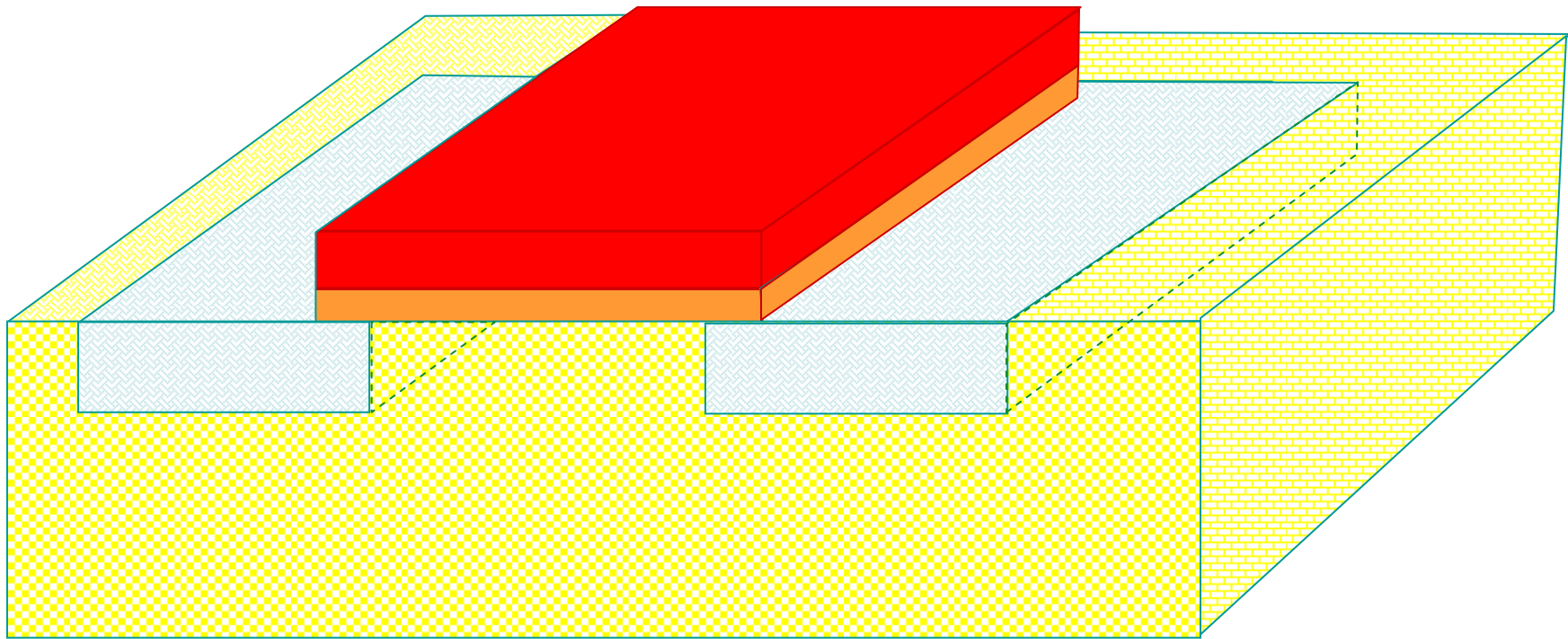
# Modeling of the MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.

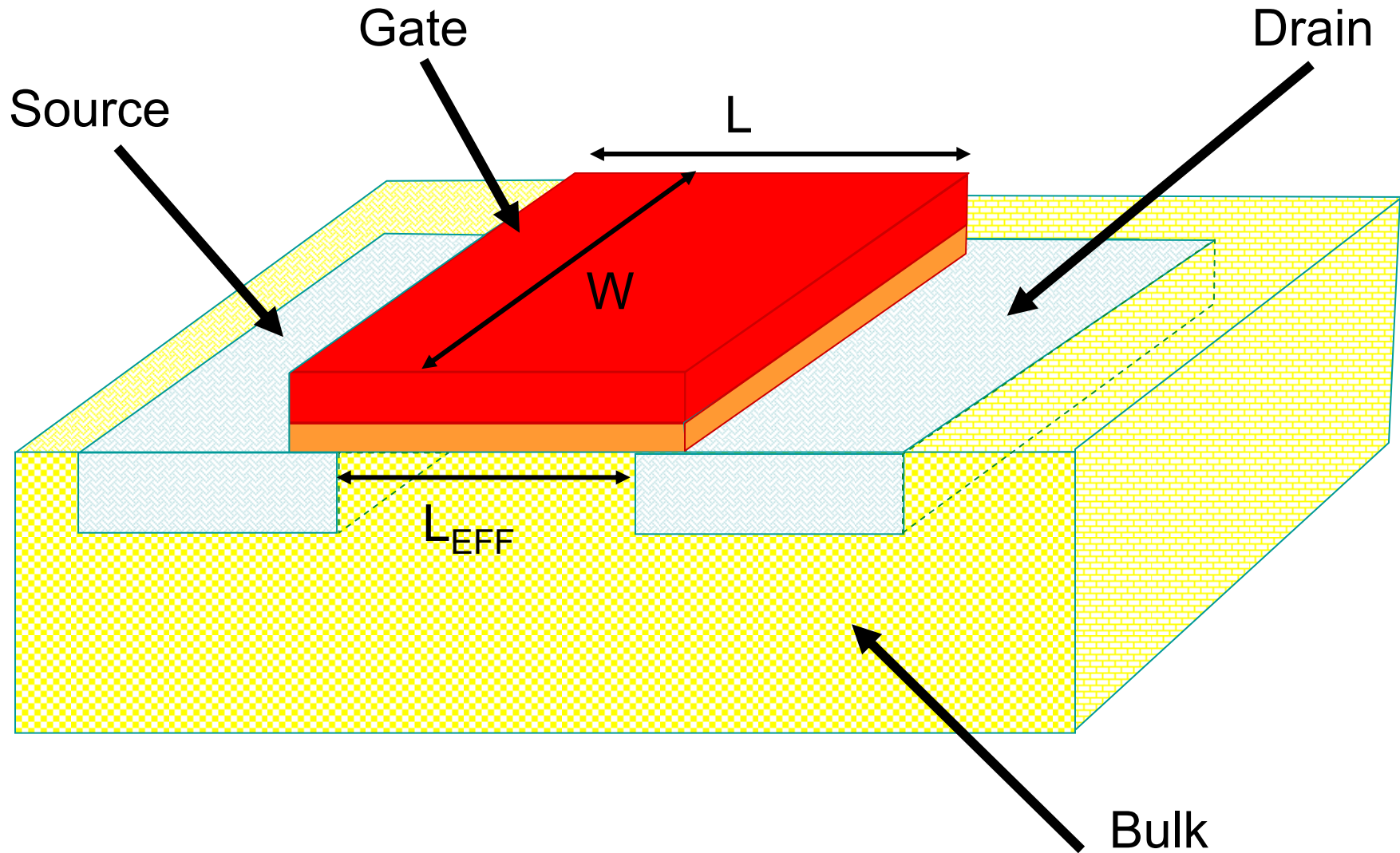
$$\left. \begin{aligned} I_D &= f_1(V_{GS}, V_{DS}, V_{BS}) \\ I_G &= f_2(V_{GS}, V_{DS}, V_{BS}) \\ I_B &= f_3(V_{GS}, V_{DS}, V_{BS}) \end{aligned} \right\}$$



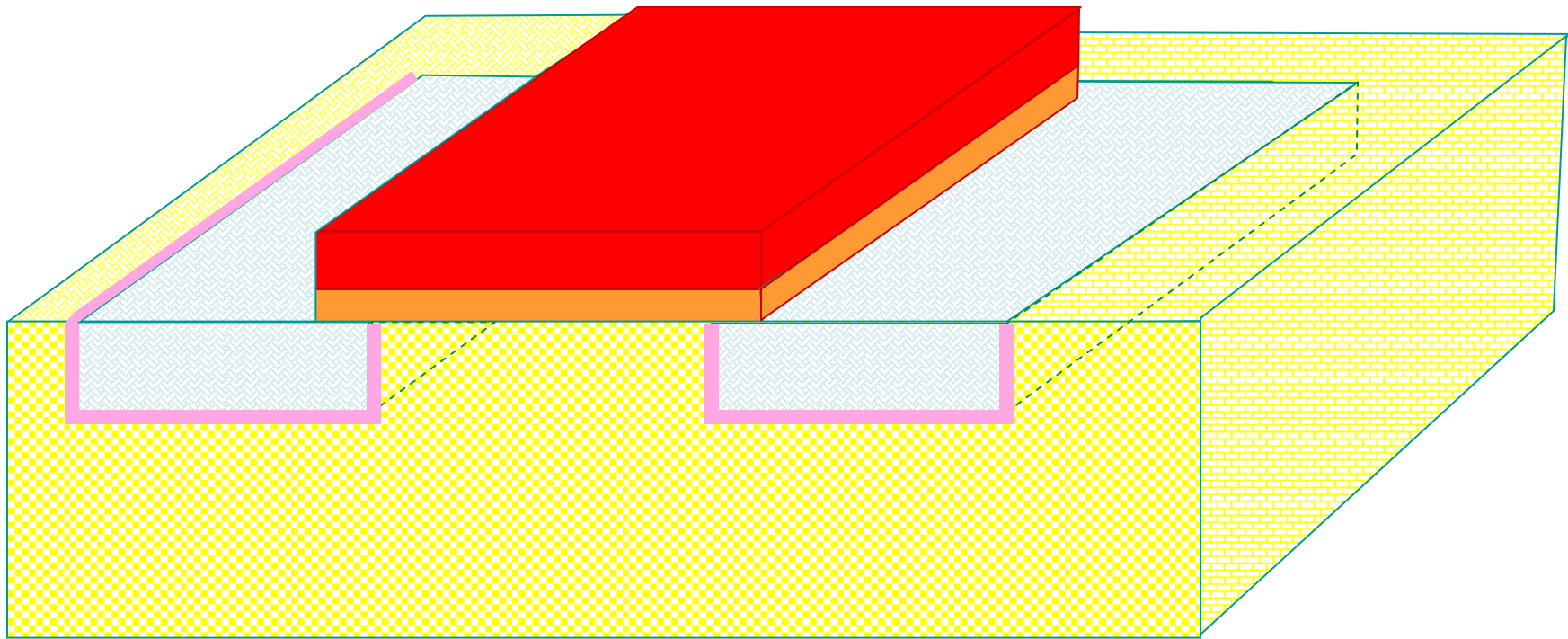
# n-Channel MOSFET



# n-Channel MOSFET

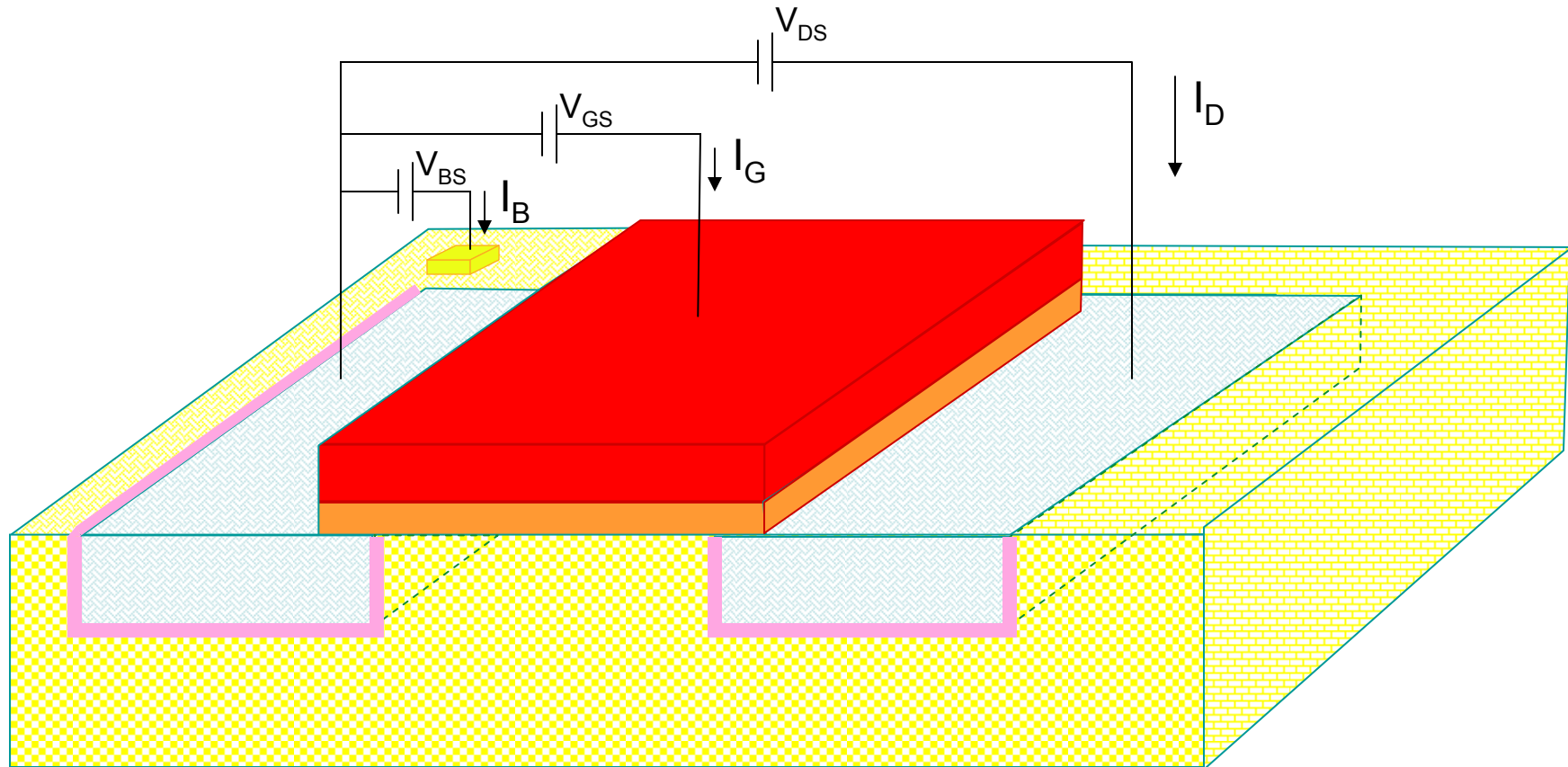


# n-Channel MOSFET



- |   |   |   |            |
|---|---|---|------------|
|  | Poly                                    |  | Gate oxide |
|  | n-active                                |  | p-sub      |
|  | depletion region (electrically induced) |   |            |

# n-Channel MOSFET Operation and Model

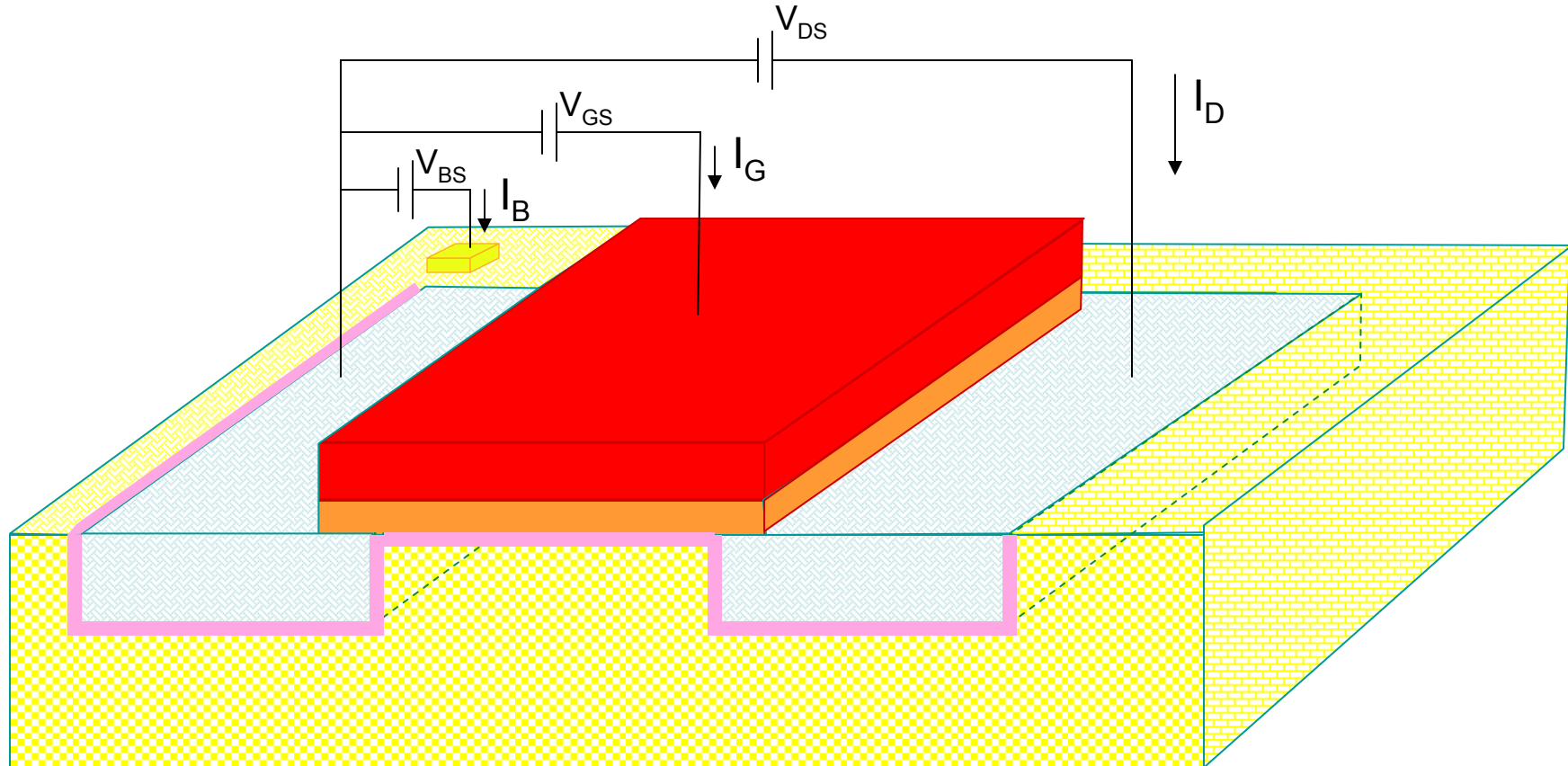


Apply small  $V_{GS}$   
( $V_{DS}$  and  $V_{BS}$  assumed to be small)

Depletion region at drain and source block current  
Termed “cutoff” region of operation

$$\begin{aligned} I_D &= 0 \\ I_G &= 0 \\ I_B &= 0 \end{aligned}$$

# n-Channel MOSFET Operation and Model

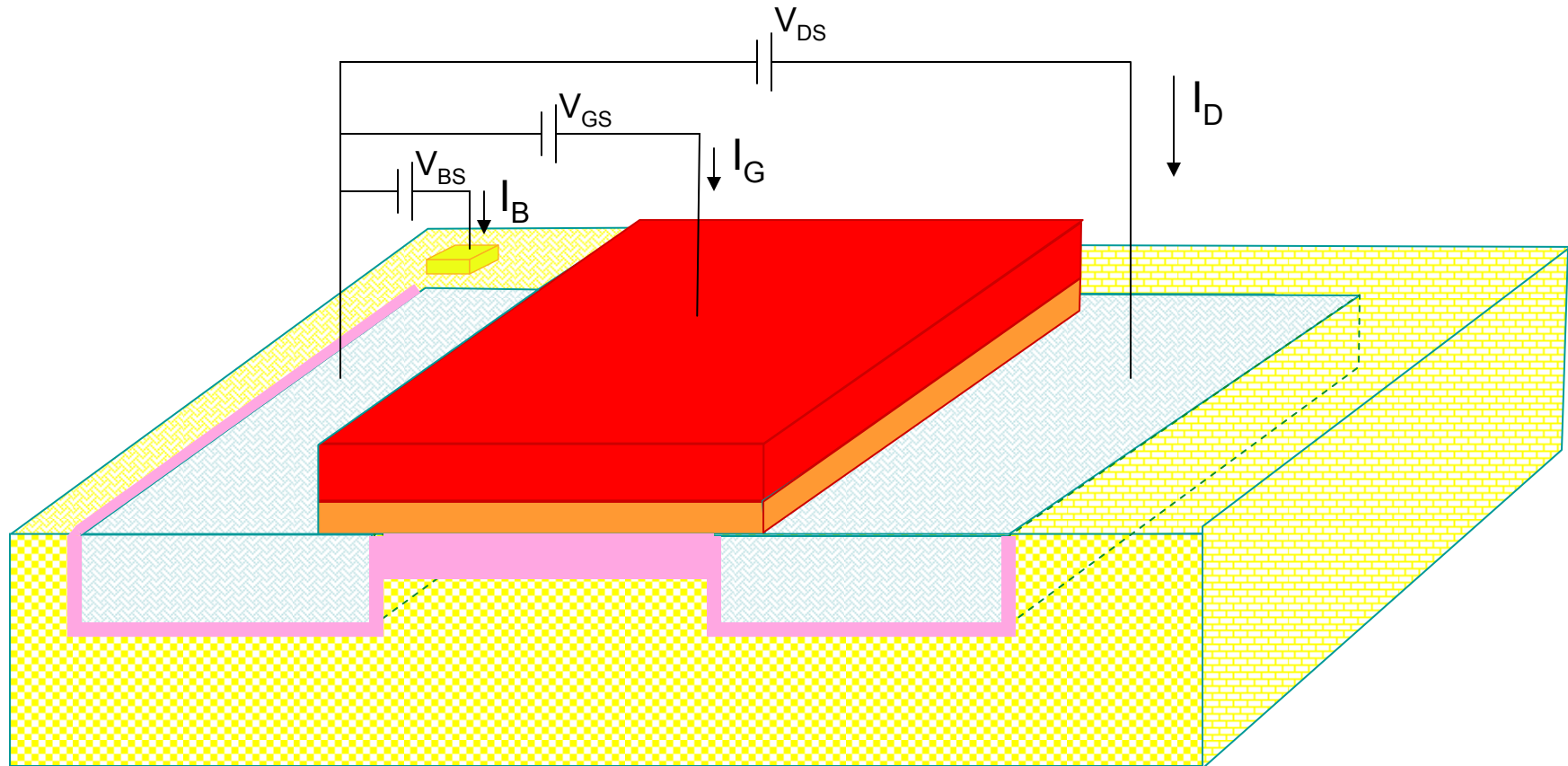


Apply small  $V_{GS}$  but a little larger than before  
( $V_{DS}$  and  $V_{BS}$  assumed to be small)

Depletion region electrically induced in channel  
Termed “cutoff” region of operation

$$\begin{aligned} I_D &= 0 \\ I_G &= 0 \\ I_B &= 0 \end{aligned}$$

# n-Channel MOSFET Operation and Model

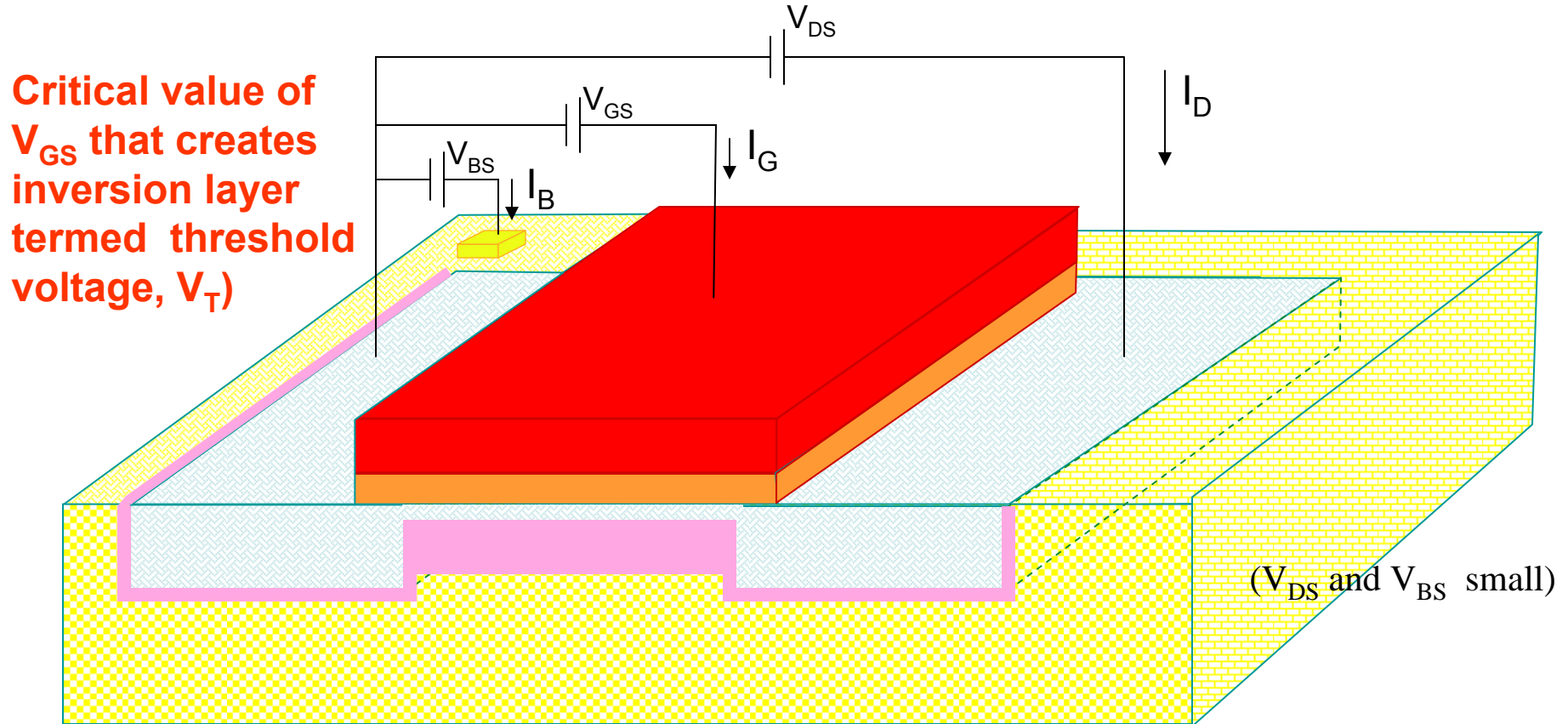


Increase  $V_{GS}$   
( $V_{DS}$  and  $V_{BS}$  assumed to be small)

Depletion region in channel becomes larger

$$\begin{aligned} I_D &= 0 \\ I_G &= 0 \\ I_B &= 0 \end{aligned}$$

# n-Channel MOSFET Operation and Model



Increase  $V_{GS}$  more

Inversion layer forms in channel

Inversion layer will support current flow from D to S

Channel behaves as thin-film resistor

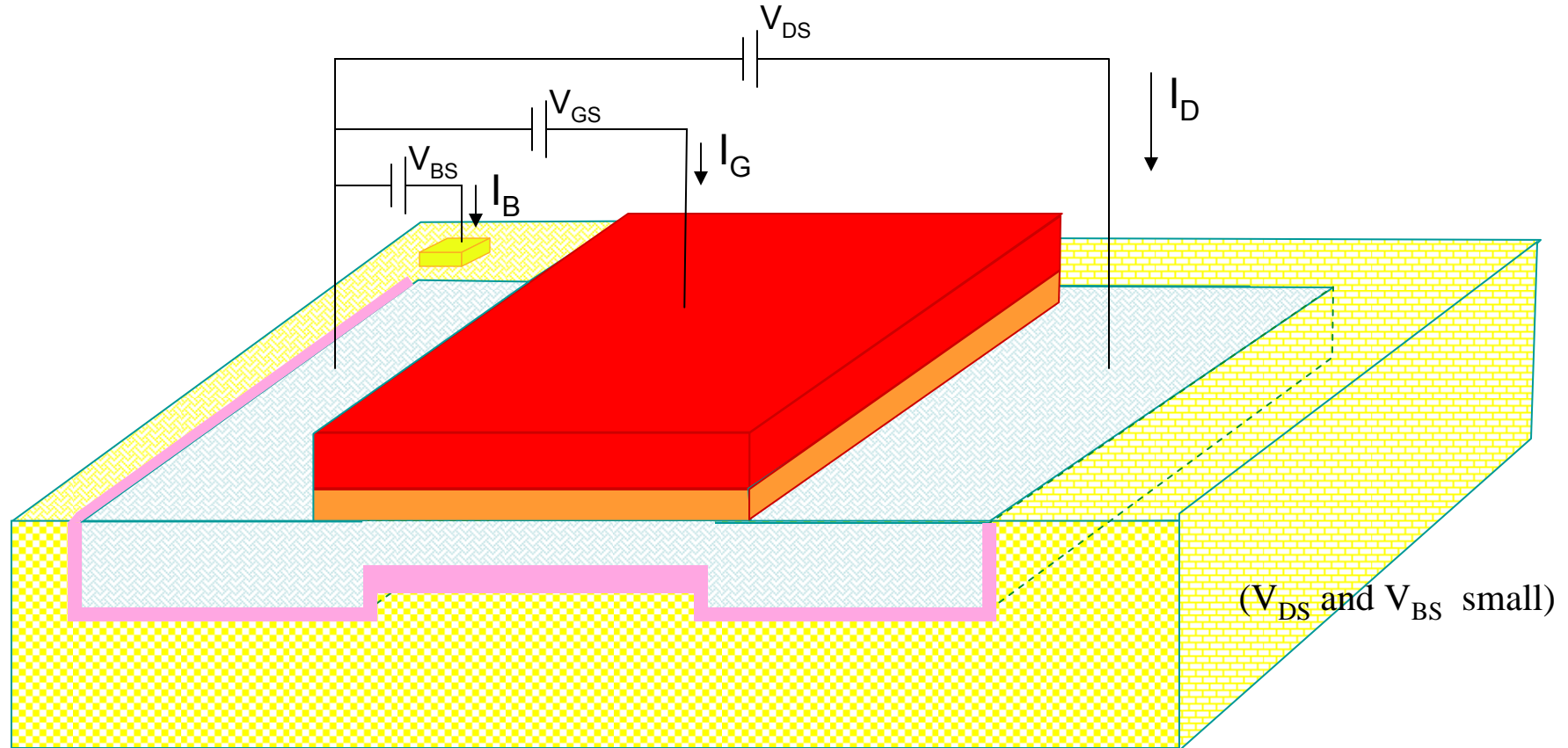
$$I_D R_{CH} = V_{DS}$$

$$I_G = 0$$

$$I_B = 0$$



# n-Channel MOSFET Operation and Model



Increase  $V_{GS}$  more

Inversion layer in channel thickens

$R_{CH}$  will decrease

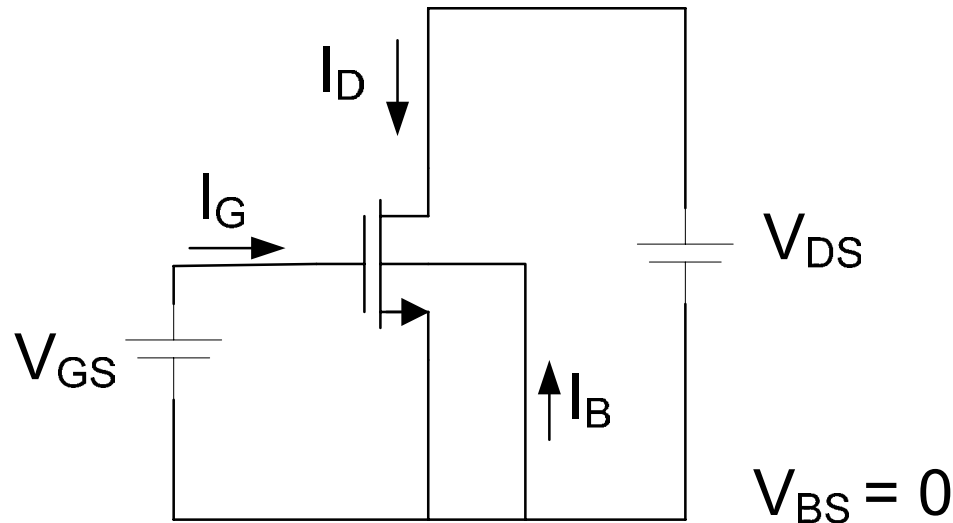
Termed “ohmic” or “triode” region of operation

$$I_D R_{CH} = V_{DS}$$

$$I_G = 0$$

$$I_B = 0$$

# Triode Region of Operation



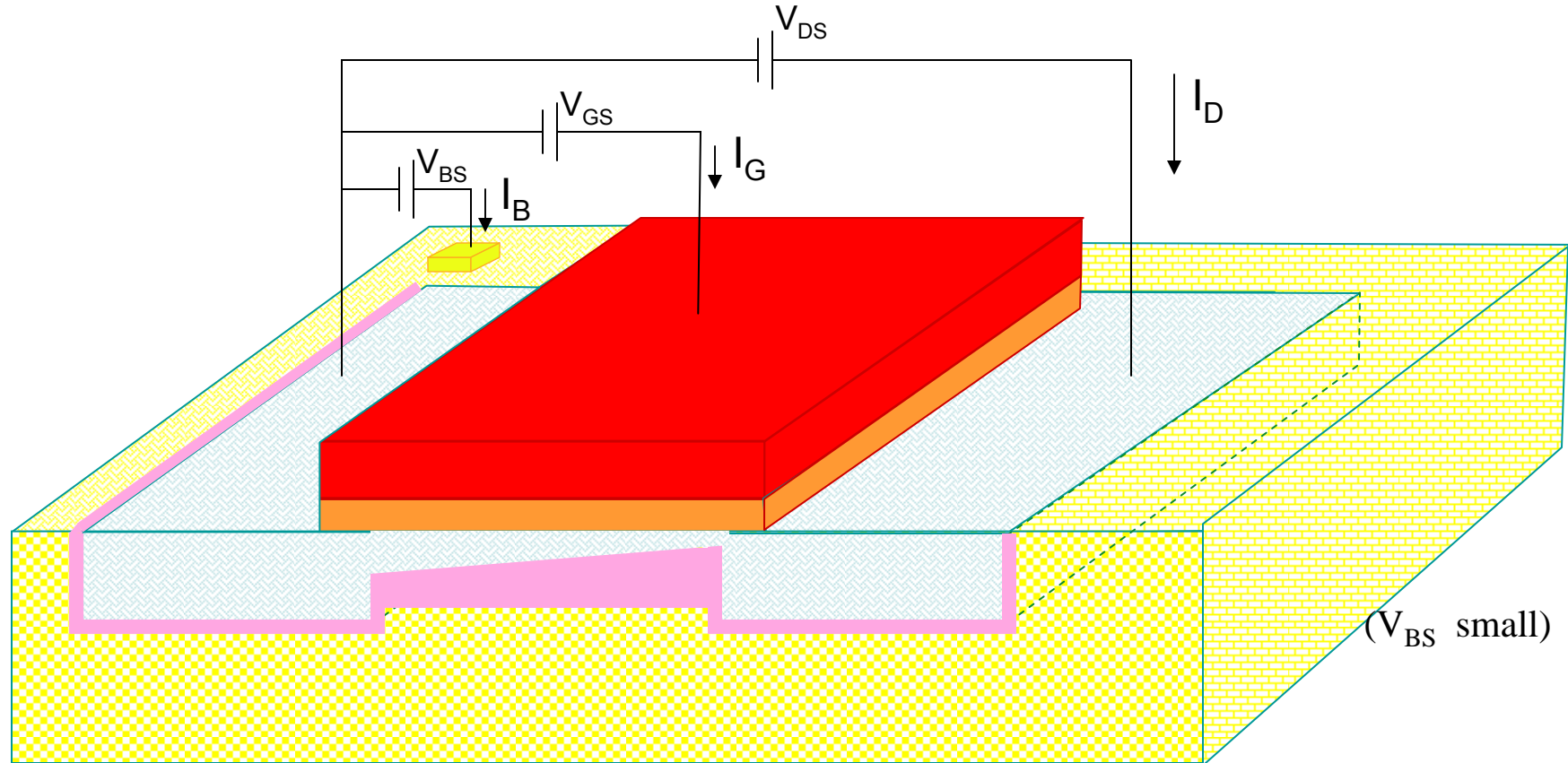
For  $V_{DS}$  small

$$R_{CH} = \frac{L}{W} (V_{GS} - V_T)^{-1} \frac{1}{\mu C_{OX}}$$

$$I_D = \mu C_{OX} \frac{W}{L} (V_{GS} - V_T) V_{DS}$$

$$I_G = I_B = 0$$

# n-Channel MOSFET Operation and Model

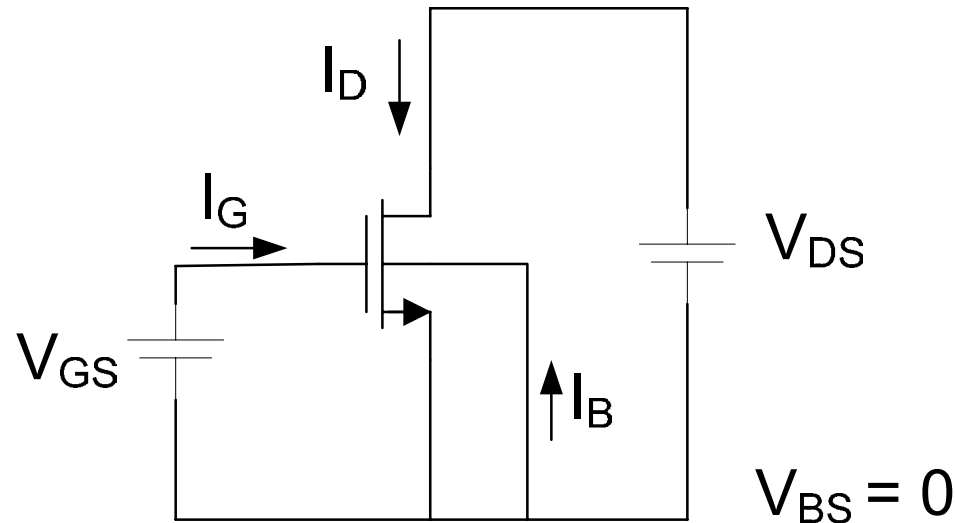


Increase  $V_{DS}$

Inversion layer thins near drain  
 $I_D$  no longer linearly dependent upon  $V_{DS}$   
 Still termed “ohmic” or “triode” region of operation

$$\begin{aligned} I_D &=? \\ I_G &=0 \\ I_B &=0 \end{aligned}$$

# Triode Region of Operation



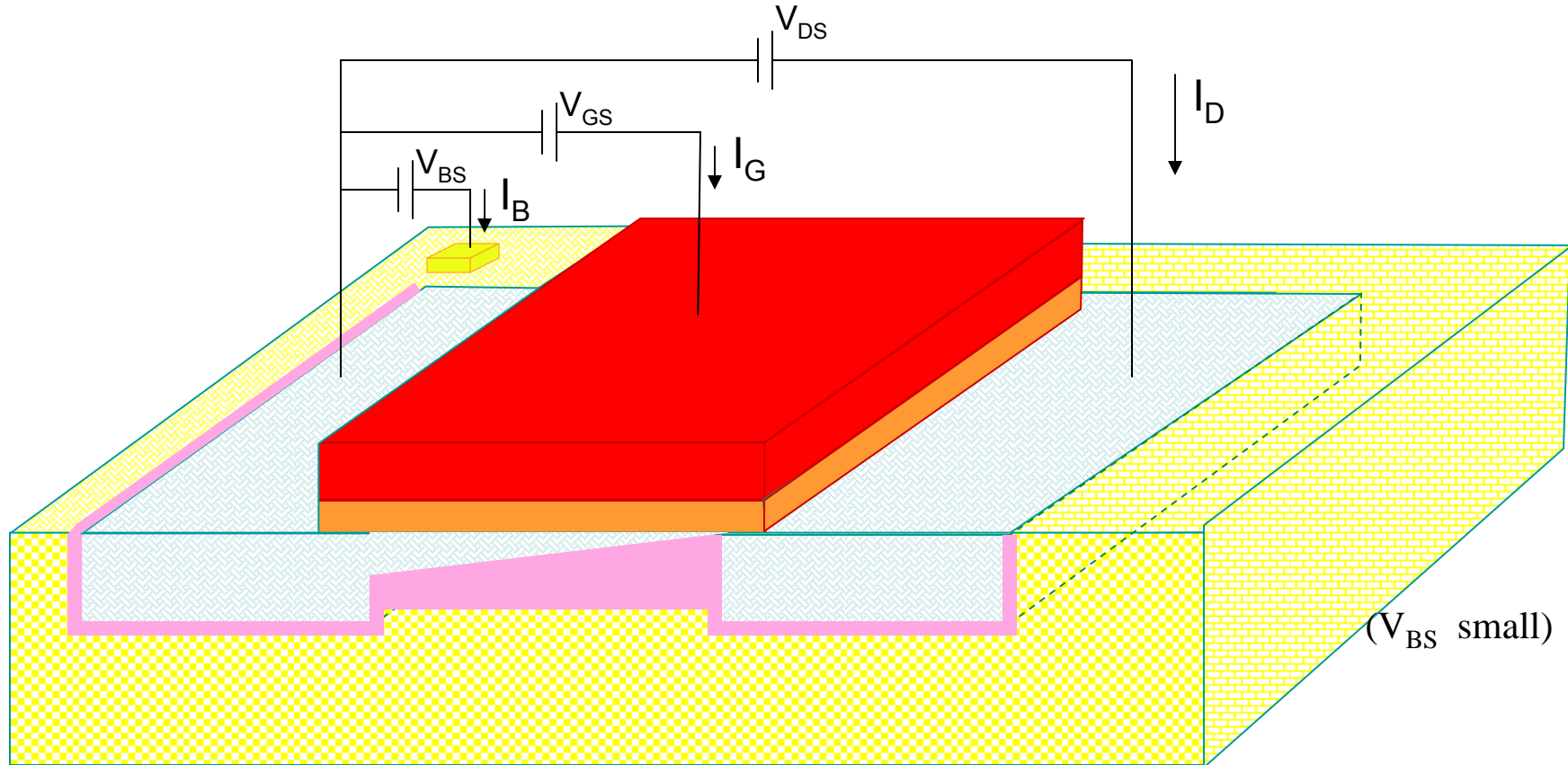
For  $V_{DS}$  larger

~~$$R_{CH} = \frac{L}{W} (V_{GS} - V_T)^{-1} \frac{1}{\mu C_{OX}}$$~~

$$I_D = \mu C_{OX} \frac{W}{L} \left( V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS}$$

$$I_G = I_B = 0$$

# n-Channel MOSFET Operation and Model



Increase  $V_{DS}$  even more

Inversion layer disappears near drain

Termed "saturation" region of operation

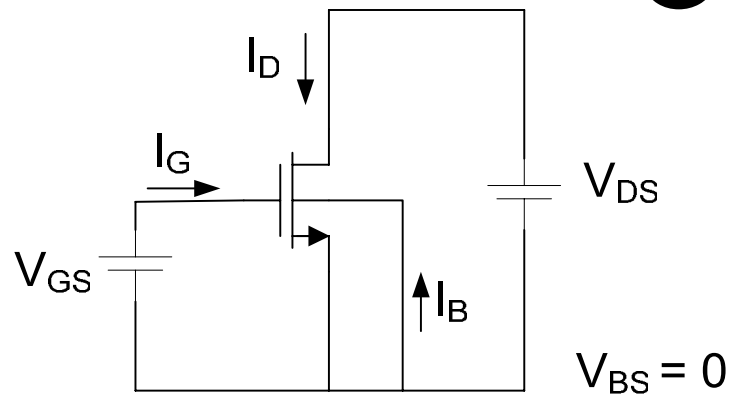
Saturation first occurs when  $V_{DS} = V_{GS} - V_T$

$$I_D = ?$$

$$I_G = 0$$

$$I_B = 0$$

# Saturation Region of Operation



$$I_D = \mu C_{OX} \frac{W}{L} \left( V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS}$$

*or equivalently*

$$I_D = \mu C_{OX} \frac{W}{L} \left( V_{GS} - V_T - \frac{V_{GS} - V_T}{2} \right) (V_{GS} - V_T)$$

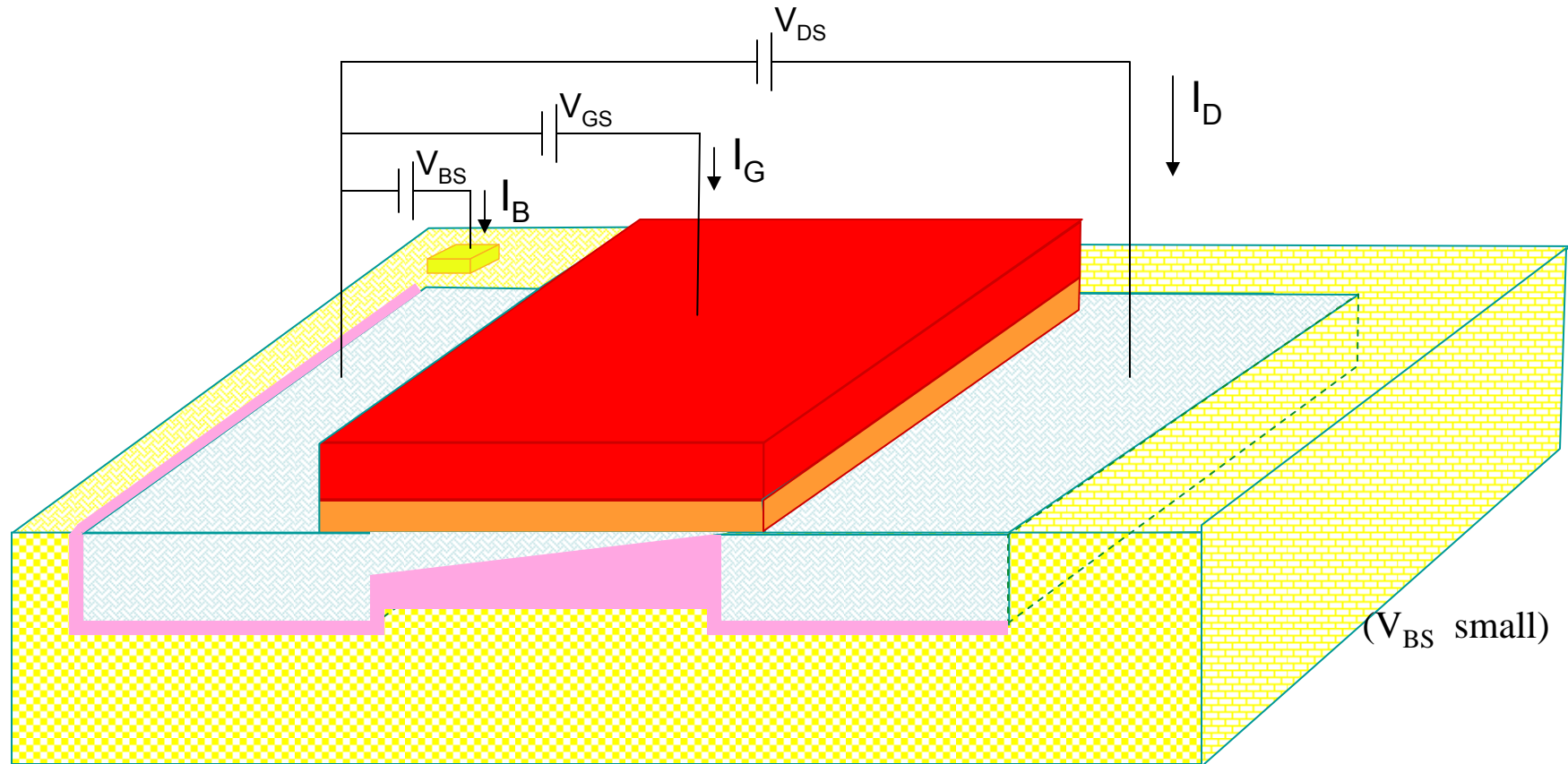
*or equivalently*

$$I_D = \frac{\mu C_{OX} W}{2L} (V_{GS} - V_T)^2$$

$$I_G = I_B = 0$$

For  $V_{DS}$  at saturation

# n-Channel MOSFET Operation and Model



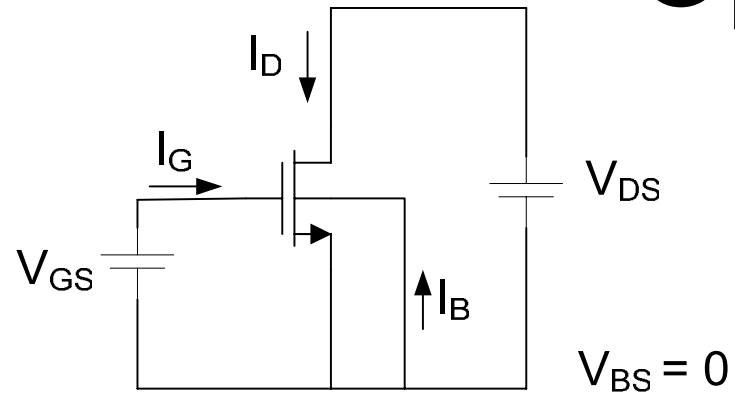
Increase  $V_{DS}$  even more (beyond  $V_{GS} - V_T$ )

Nothing much changes !!

Termed “saturation” region of operation

$$\begin{aligned} I_D &=? \\ I_G &=0 \\ I_B &=0 \end{aligned}$$

# Saturation Region of Operation



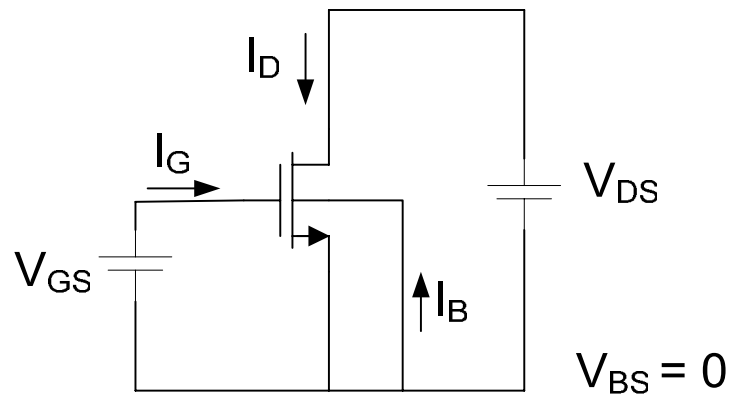
For  $V_{DS}$  in Saturation

$$I_D = \frac{\mu C_{OX} W}{2L} (V_{GS} - V_T)^2$$

$$I_G = I_B = 0$$



# Model Summary



$$I_D = \begin{cases} 0 & V_{GS} \leq V_T \\ \mu C_{OX} \frac{W}{L} \left( V_{GS} - V_T - \frac{V_{DS}}{2} \right) V_{DS} & V_{GS} \geq V_T \quad V_{DS} < V_{GS} - V_T \\ \mu C_{OX} \frac{W}{2L} (V_{GS} - V_T)^2 & V_{GS} \geq V_T \quad V_{DS} \geq V_{GS} - V_T \end{cases}$$

Note: This is the third model we have introduced for the MOSFET

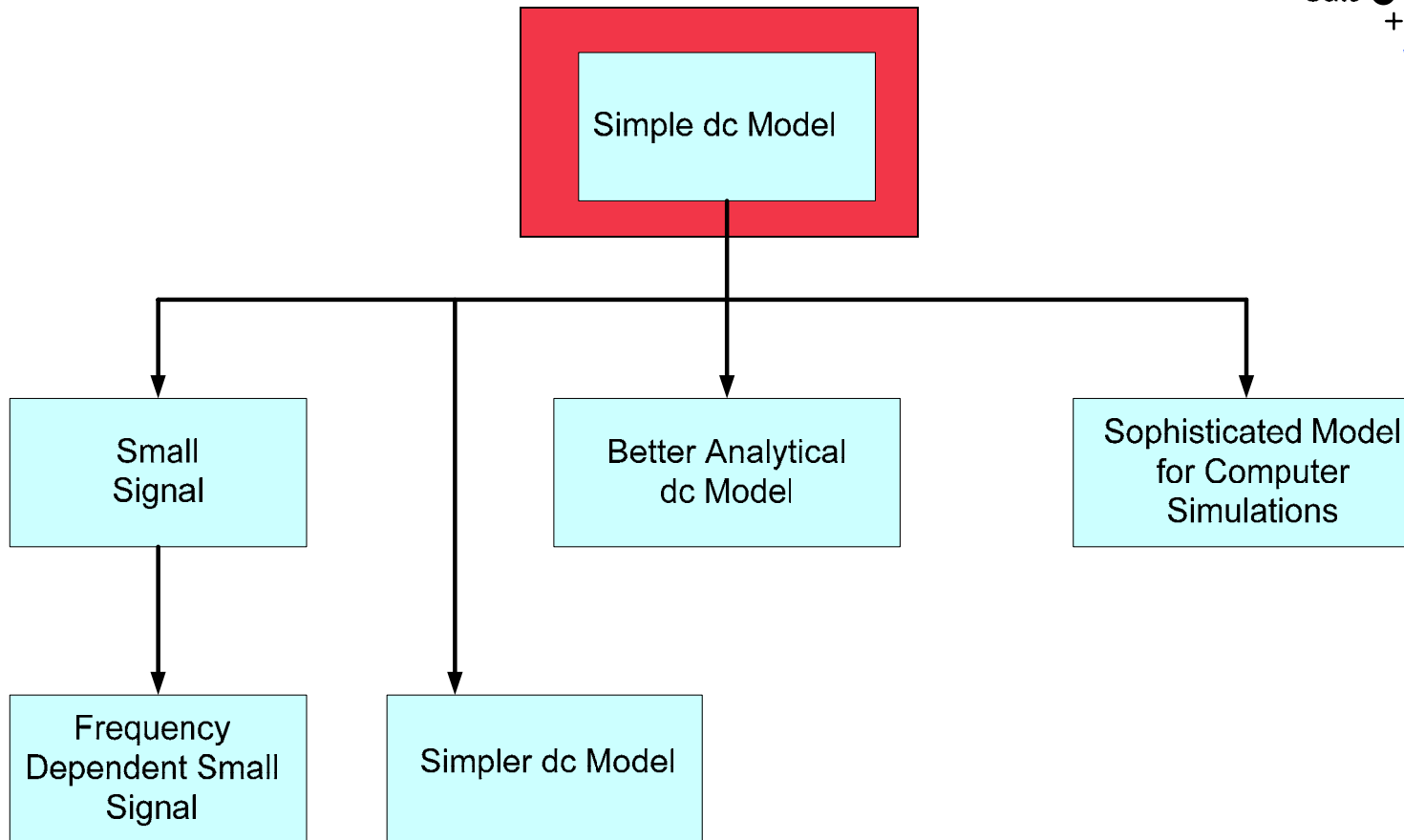
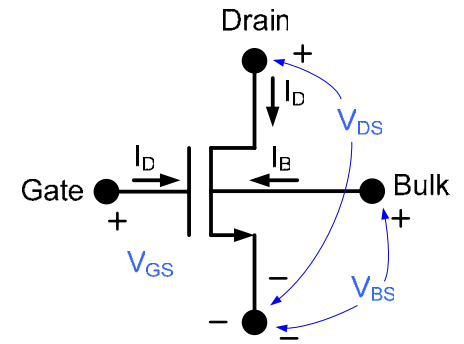
# Modeling of the MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.

$$I_D = f_1(V_{GS}, V_{DS}, V_{BS})$$

$$I_G = f_2(V_{GS}, V_{DS}, V_{BS})$$

$$I_B = f_3(V_{GS}, V_{DS}, V_{BS})$$



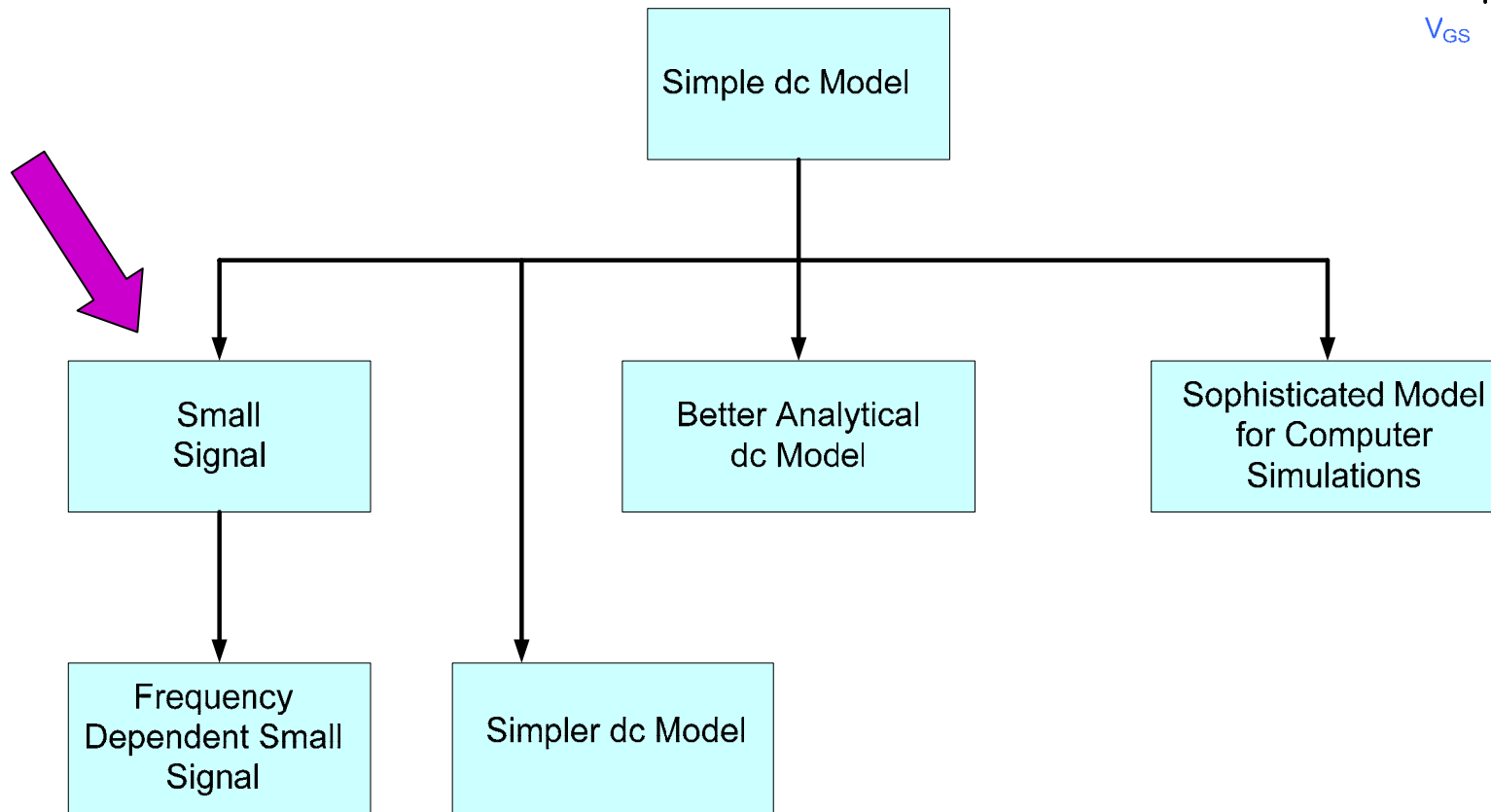
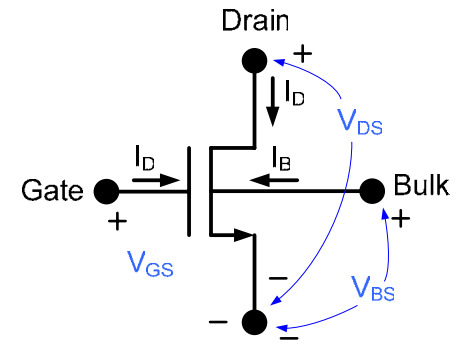
# Modeling of the MOSFET

Goal: Obtain a mathematical relationship between the port variables of a device.

$$I_D = f_1(V_{GS}, V_{DS}, V_{BS})$$

$$I_G = f_2(V_{GS}, V_{DS}, V_{BS})$$

$$I_B = f_3(V_{GS}, V_{DS}, V_{BS})$$



**End of Lecture 15**